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(71) Applicant: NISSIN ELECTRIC CO LTD

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(72) Inventor: NAITO KATSUO
TANJO MASAYASU

(54) MEASURING APPARATUS FOR BEAM
QUANTITY

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(57) Abstract:

PROBLEM TO BE SOLVED: To obtain a measuring apparatus by which the beam quantity of an ion beam can be measured precisely by a method wherein, even when secondary ions and secondary electrons are generated inside a Faraday cup, they are suppressed from escaping from the Faraday cup.

SOLUTION: A Faraday cup 20 has a structure in which it is divided electrically into a cylindrical sidewall part 21 and a bottom part 22 which catches an ion beam 2. A beam ammeter 12 is connected to the bottom part 22. In addition, a DC power supply 24 which applies a positive voltage to the sidewall part 21 is installed across the sidewall part 21 and the bottom part 22. In addition, the bottom part 22 is formed in a shape which is sharpened toward a side on which the ion beam 2 is incident.

